

[10191/955]

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANTS:

Joerg SCHAEFER, et al

SERIAL NO.:

09/238,262

FILED:

January 27, 1999

TITLE.

METHOD OF PRODUCING STRUCTURED WAFERS

ART UNIT:

1746

EXAMINER:

Anita K. Alanko

D.C. 20231, on

Assistant Commissioner for Patents

Washington, D.C. 20231

<u>AMENDMENT</u>

Sir:

In response to the Office Action dated January 30, 2001, please reconsider the abo identified application based on the following:

IN THE CLAIMS:

Please amend Claim 5 as follows:

(Twice Amended) The method according to claim 2, wherein the photoresist technique 5. used is an integrated circuit photoresist technique.

REMARKS

Claims 1-9 are pending in the present application. Applicants have made corrections to overcome the objections/rejections in the instant patent application. No new matter has been added. It is respectfully submitted that all of the presently pending claims are allowable and reconsideration of the present application is requested for the following reasons.

Objection to Claim 5

Claim 5 was objected to under 37 CFR § 1.75(c) as being of improper dependent form for failing to further limit the subject matter of a previous claim.

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